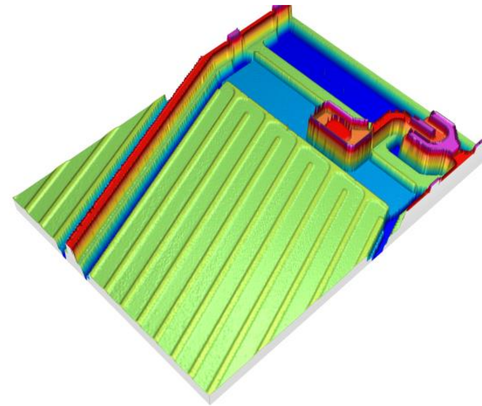
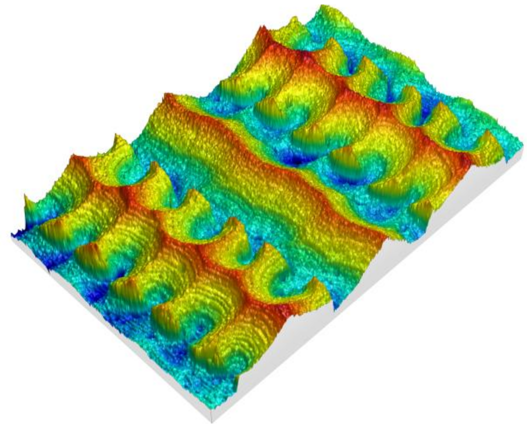
NanoSystem
www.nanosystemz.com





NV-1800 Surface Profiling System

Accurate Non-Contact Surface Topography

Superior non-destructive 3D Surface Profiling and Analysis

Easy-to-Use Platform Delivers Rapid and Efficient Process Monitoring

Comprehensive and Intuitive software Provides Sample and Application Flexibility

Specification

Measuring method	White-Light Scanning Interferometry(WSI), Phase Shift Interferometry(PSI)
F.O.V Lens	1.0x (Default)
Scanning Range	MAX 270um (PZT Scanning)
Scanning Velocity	7.2um/sec,
Vertical Resolution	WSI : < 0.5nm / PSI : < 0.1nm
Lateral Resolution	0.2 ~ 4um (Objective Lens Dependent)
Illumination	White-light LED Illumination
Tip / Tilt	±3° (Stage Tip/Tilt)
Interferometric Objectives	Single Lens Available
Step Height Repeatability	0.2% @1σ
X,Y Stroke	50x50mm (Manual)
Z Stroke	30mm (Manual)
Stage Size	150x150mm

Option

F.O.V Lens	0.55x, 0.75x, 1.0x, 1.5x, 2.0x (Selectable)
Interferometry Objectives	2.5x, 5x, 10x, 20x, 50x, 100x (Selectable)
Scanning Range	Max 10mm available
Vaccum Stage	Option

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